ULVAC's History

Since its establishment in 1952, ULVAC has consistently advanced by leveraging its core technology-cuttingedge vacuum technology-to address the social issues of each era. Moving forward, ULVAC remains committed to its Fundamental Management Philosophy, continuing to contribute to the progress of industry and science through the comprehensive utilization of vacuum technology.



1952-1970 High economic growth period

Industrial restoration and convenience in daily life Contributed to industries supporting people's lives through vacuum equipment

1952 Established Japan Vacuum Engineering Co., Ltd. 1955 Opened the Omori Plant in Tokyo to start manufacturing equipment in Japan.

- 1959 Opened the Yokohama Plant.
- 1964 Established the first overseas subsidiary in Hong Kong
- 1968 Head Office/Plant completed in Chigasaki, Kanagawa Prefecture

Contribution to the Resolution of Social Issues

- Developed vacuum arc furnaces for stainless steel and other steel manufacturers contributing to industrial restoration
- Developed vacuum melting and casting furnaces for nuclear power development, contributing to the solution of energy issues.
- Developed highly sensitive vacuum gas analyzers for direct analysis of air pollution.
 Delivered a large-scale space chamber to the Institute of Space and Astronautical
- Science (ISAS) at the University of Tokyo, contributing to space development. Developed vacuum freeze-drying equipment for instant foods, contributing to improving dietary habits.

1971-1990 Development of electronics

Comfortable working environment

In line with increasing demand for semiconductors, a stream of ULVAC products gained top shares in the global market.

1972 Opened the Institute for Super Materials as ULVAC's first research facility. 1975 Established a local subsidiary in North America as a base for exports to the U.S 1982 Established a subsidiary in Taiwan.

- 1983 Opened the Beijing Office in China. 1990 Opened the Fuji Susono Plant in Shizuoka Prefecture as a dedicated plant for semiconductor production equipment.

Contribution to the Resolution of Social Issues

- Delivered a vacuum pumping system for a critical plasma tester to the Japan Atomic Energy Research Institute.
- Developed transparent conductive film deposition equipment for LCDs for calculators • Developed the world's first multi-chamber deposition system for semiconductor
- memory. • Delivered the world's first computer-controlled vacuum deposition system for
- semiconductors to IBM. • Developed sputtering equipment for hard disk deposition, making a significant contribution to the enhancement of computer performance

1991-2010 Information society, spread of digital home appliances

High-performance devices

ULVAC grew significantly in line with the expansion of the FPD market from Japan to South Korea and Taiwan.

- 2001 Changed the company name to ULVAC. Inc.
- 2003 Established a full-scale production and service base in China
- 2004 Listed on the First Section of the Tokyo Stock Exchange. New buildings of the Head Office/Plant (Chigasaki) completed. 2005 Opened the Chiba Tomisato Plant for the development and manufacturing of materials.

Contribution to the Resolution of Social Issues

Developed the CERAUS series of multi-chamber deposition systems for semiconductors.

- Developed the SMD series of sputtering systems for LCDs, contributing to mass production of laptop PCs. It subsequently became the foundation for the popularization of flat-screen TVs.
- Developed deposition equipment for OLEDs, a next-generation display technology. Developed an ion implantation system for mass production of power devices.
- Developed an integrated production of power device contributing to energy efficiency.
 Developed the ECO-SHOCK power-saving attachment for dry pumps.
 Developed an integrated production line for thin-film solar cells to meet the demand for renewable energy.

2011-Present Digital society

Sustainable future

Contributing to a wide range of fields by leveraging strengths as a comprehensive vacuum equipment manufacturer in line with the spread of mobile devices and the development of ICT

2011 Established the South Korea Institute for Super Materials Research. 2015 Established the Future Technology Research Laboratory.

- 2018 Opened the ULVAC-Osaka University Joint Research Institute for Future Technology at Osaka University.
- 2021 Opened the ULVAC Advanced Technology. Collaborative Research Cluster at
- Institute of Science Tokyo. 2022 Listed on the Prime Market of the Tokyo Stock Exchange
- 2024 Established Technology Center PYEONGTAEK in South Korea.

Contribution to the Resolution of Social Issues

- The development of thin-film lithium metal anodes utilizing vacuum deposition technology has been selected for a project under the NEDO Green Innovation Fund Project, specifically vithin the "Next-Generation Storage Battery and Motor Development"
- The ULVAC-Osaka University Joint Research Institute for Future Technology at Osaka University is conducting basic research in the regenerative medicine and
- energy fields and accepts students for Japan's first corporate co-creation program The ULVAC Advanced Technology Collaborative Research Cluster at Institute of
- Science Tokyo aims at co-creation, such as human resources development and ntegration of plasma diagnostics technology with AI technology.
- Developed extreme ultraviolet (EUV) lithography-ready sputtering equipment for Metal Hard Mask (MHM) process, contributing to mass production of highspeed, low-power-consumption advanced logic devices.

of establishment (1952) (1968)

Fuii Susono Plant (1990)

Tokyo Stock Exchange (2004)

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